

an imager that receives x-rays from said object based on said emitted x-rays and forms an image of said object, wherein said imager comprises a semiconductor imager;

an imager support system that attaches said imager to a support structure, wherein said imager support system comprises:

*x<sup>1</sup>  
contd.*  
a first arm having one end attached to said imager and another end attached to said support structure; and

a second arm having one end attached to said imager and another end attached to said support structure.

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63. (Amended) A method of treating an object with radiation, comprising:

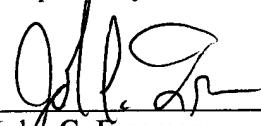
*x<sup>2</sup>*  
move a radiation source about a path;  
direct a beam of radiation from said radiation source towards an object;  
emitting an x-ray beam in a cone beam form towards an object;  
detecting x-rays that pass through said object due to said emitting an x-ray beam  
with an amorphous silicon flat-panel imager;  
generating an image of said object from said detected x-rays; and  
automatically controlling said path of said radiation source based on said image.

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94. (New) The method of claim 63, wherein said object is located at a position during said emitting and said detecting and remains at said position during said controlling.

Please note that claim 94 is being added in order to provide additional coverage for a method of treating an object with radiation. Accordingly, new claim 94 is not being added for reasons of patentability as defined in Festo Corporation v. Shoketsu Kinzoku Kogyo Kabushiki Co., Ltd., 234 F.3d 558, 56 USPQ2d 1865 (Fed. Cir. 2000).

Respectfully submitted,



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